

ABSTRACT

On a substrate (7) are configured piezoelectric elements (2) composed of a mirror device (1), piezoelectric thin films (3), electrodes (4a, 4b, 4c), and elastic members (5), and application of a voltage to the electrodes causes flexure deformation in the piezoelectric thin films, so that the mirror device is actuated. A plurality of the piezoelectric elements are arranged in parallel with a longitudinal direction (8) thereof, and torsion springs (6) are provided so as to extend in a direction orthogonal to the longitudinal direction and so as to hold the mirror device in connection with the substrate. The mirror device is connected to the piezoelectric elements through strain absorbers (10). In such a configuration, the torsion springs serve as a rotation axis (9), and the mirror device is inclined about the rotation axis.